## SLICING OF SILICON INTO SHEET MATERIAL

Silicon Sheet Growth Development for the Large Area Silicon
Sheet Task of the Low Cost Silicon Solar Array Project
Sixth Quarterly Report

By
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September 30, 1977

## MASTER

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## Varian Associates

Lexington Vacuum Division
Lexington, Massachusetts


## U.S. Department of Energy

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Silicon Sheet Growth Development for the Large Area Silicon Sheet Task of the Low Cost Silicon Solar Array Project

SIXTH QUARTERLY REPORT

## By

S. C. HOLDEN
J. R. FLEMING

September 30, 1977

Reporting Period June 18, 1977 to September 18, 1977

JPL Contract No. 954374

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### 1.0 SUMMARY

The "Multiple Blade Alignment Device" has been reported to JPL as a New Technology item, and is currently being reviewed for patent potential. The device has proven difficult to install on a blade package. Successful engagement of the device has resulted in an intrinsic parallelism of the ends of the package to within $3 \mu$, compared to standard errors prior to correction of over 50\%. Measurements of blade misalignment indicate an average runout of $50 \mu$ in a 220 blade package. This compares well with predictions based on thickness variation measurements of blades and spacers.

Early cutting tests with 0.15 mm blades and 10 cm diameter ingots show lower yield and accuracy and higher cutting speed than previous standard tests. This seems to be a result of effective high abrasive concentration on the blades as a result of the slurry application technique. A similar, more dramatic reduction of yield occurs with a thin slurry oil. This appears to occur by increased slurry transport to the blades and another effective increase of : jrasive packing to the cutting region.

Design of the large capacity MS saw is proceeding well, with a final conceptual design in progress. A flywheel system for work-piece drive is described. The design offers a practical conservative motion for the drive, requiring a minimum of power.

10 cm MS slices hive been sent out for solar cell fabrication. 10 cm diameter and 2 cm square MS slices have been delivered for various surface preparations, and will be fabricated into cells and evaluated for performance. This will develop a minimum surface removal technique for both the damage and profiles peculiar to thin MS slices while allowing high efficiency cell production.

## 3.0

INTRODUCTION
This contract has as an objective the development of MS slicing as a low cost technique for the slicing of silicon for solar cells. The goals of this second phase of work are an add-on cost of MS slicing of less than $\$ 10 / \mathrm{m}^{2}$ and a conversion rate from ingot to sheet of $1.0 \mathrm{~m}^{2} / \mathrm{kg}$ with $10-12 \mathrm{~cm}$ diameter silicon ingot.

The conversion capabilities were demonstrated in the first phase of work. The major sources of cost reduction are the reduction of cost for expendable materials and the increase of specific labor and saw output by increasing the multiple blade capacity by three times.

A major problem to be dealt with is the statistically predictable misalignment of blades within a multiple blade package. This problem reduces cutting stability and yield with larger numbers of blades, lower precision (lower cost) blade stock and thinner blades. A solution has been devised and is in a testing and development stage. The blade alignment technique is the key to this program.

## CUTTING TESTS

Table 1 shows a summary of the conditions and results of cutting tests during the past quarter. Tests involved cutting for solar cell fabrication, testing of various abrasive and oil combinations and evaluation of improved blade alignment by correction of the end stop of the saw's bladehead. Two standard Varian 686 wafering saws are used in this test program, and are designated as machines \#2 and \#4. Saw \#2 is intended for blade alignment device testing, blade hardness and accuracy tests, and development of miscellaneous techniques. Saw \#4 is used exclusively for testing of oil and abrasive slurries. Because of the difficulties encountered with the blade alignment device, the bladehead of saw \#2 has been tied up in non-cutting development.

A package of 1500.15 mm thick blades and 0.41 mm spacers was used to cut a 10 cm silicon ingot. A change from \#600 SiC abrasive (standard) to \#500 SiC resulted in a cutting time of 24.5 hours, but an increase in kerf loss for 0.20 mm (with $\# 600$ ) to 0.24 mm . Yield was $67 \%$, and slice bow and taper averaged $35 \mu$, which indicates a good controlled cutting action. However, the shift to the heavier abrasive gave an increase in kerf loss comparable to that saved by reducing blade thickness from 0.20 mm to 0.15 mm .
3.2 Lubrizol Suspension 0il: Test \#2-3-02

Several tests were run using Lubrizol 5985, a suspension oil supplied by Lubrizol Corporation as a replacement for the standard PC oil. This test was run using 0.15 mm blades and 0.30 mm spacers. All conditions (tensioning, abrasive mix, abrasive, feed weight, etc.) were "standard", i.e. set at the values found to be best for PC oil.

Severe wafer breakage occurred during cutting. The yield was about $3 \%$. The machine was checked for alignment, and it was found that the end of the bladehead well (against which the end of the blade pack is compressed) was significantly out of perpendicular relative to the feed ( 50 to 80 microns in 12 mm ). The end blocks were shimmed to make them perpendicular to wi-thin $2.5 \mu \mathrm{mI}\left(.0001^{\prime \prime}\right)$ and the test was repeated.
3.3 Lubrizol Suspension 0il: Test \#2-3-03

Test \#2-3-02 was repeated, except the spacers were increased to . 356 mm (.014") in order to increasc wafer strength. The operator had difficulty aligning the blade pack, but was able to obtain alignment within tolerances (having the blade pack parallel to the stroke within $5 \mu \mathrm{~m}$ (.0002")).

Again, severe wafer breakage occurred during cutting. The yield was about $25 \%$. The wafer surfaces were quite wavy, and some broken wafers were measured to be .102 mm (.004") thick. These results indicated that controlled cutting had not been achieved.

The question is "can controlled cutting be achieved with Lubrizol 5985"? The major differences between 5985 and PC (standard) are viscosity and suspension power. It is difficult to believe that the much higher suspension power of 5985 is detrimental; thus, the lower viscosity of 5985 is probably the major difference.

Viscosity affects mostly the drag forces and the abrasive transport quality during cutting. Lower viscosity should decrease drag forces; again, this should not be detrimental.

Therefore, the poor performance of 5985 is likely to be due to a change in the transport and distribution of abrasive. We intend to experiment further with 5985, trying different abrasive mixes, until we obtain controlled.cutting. We hope that this will be achieved at a lower abrasive mix, yielding a potentially cheaper slurry. We also hope that the higher suspending power of 5985 may allow the slurry to be used longer than a PC slurry, again reducing costs.

We are investigating two more possibilities for suspension agents. We have obtained some of the polymeric suspension agent used in 5985, and intend to mix our own cheaper oils by using lower concentrations of suspension agent. Since 5985 will suspend abrasive for a month or more, we feel that 5985 may have excessive suspension power and, consequently, excessive costly additive. Also, the Lubrizol Corporation has shown interest in trying to develop a water-based suspension agent.

### 3.4 Abrasive Mixture \#500/\#600/\#800 SiC: Test \#2-3-04

A mix of three abrasive sizes was used to cut a 10 cm silicon ingot, with $1 / 3$ of the standard mix ( $0.36 \mathrm{~kg} / 1 i t e r$ ) made of \#500, \#600 and \#800 SiC. Total cutting time was only 22.1 hours, less than with only \#500 SiC. However, bow and taper were not as low as in \#2-3-01 and kerf loss was nearly identical ( 0.246 mm ). Yield was $83 \%$, indicating a reasonably controlled cutting action. The results indicate two aspects of MS slicing. Firstly, it appears that the largest particles in an abrasive mix control the cutting action and kerf loss. Secondly, the abrasive mix involving a broader range of particle size seems to maintain good cutting action. It is possible that the smaller particles help support the larger particles and allow them to perform their optimum cutting action. Similar broad particle size testing will be performed with \#600 SiC as the largest abrasive size.
3.5 Cell Fabrication, 10 cm Diameter: Test \#2-4-01
0.15 mm blades and 0.36 mm spacers were used to cut a 10 cm silicon ingot with a standard $0.36 \mathrm{~kg} /$ liter mix of \#600 SiC with PC oil and 85 grams of cutting force per blade. Cutting time was 22.4 hours and yield of the 0.314 mm slices was only $59 \%$. Taper and bow were $70 \mu$. It was felt that blade stop alignment may have impacted yield in this test. Alignment, as described previously was carried out to try to correct this condition.
3.6 Machine Proof Test: Test \#2-4-02

After end ston rorrertion, the above test (\#2-4-01) was repeated. 0.41 mm spacers were used resulting in 0.36 mm slices. Cutting time was again 22.4 hours with $50 \%$ yield.

Bow and taper were $50-70 \mu$. The indication was that proper alignment existed, but that uncontrolled cutting leading to low yield had occurred.

The best explanation for poor cutting lies in the different slurry application technique used with the present test saws. A reciprocating slurry application, as opposed to pulse-type distribution, seems to increase the effective slurry mix. Higher mix generally has given reduced cutting time and wafer yield and accuracy. The preceding tests show these conditions. A shift to a pulse-type slurry applicator will show this effect.

### 3.7 Wafer Dicing, Cell Fabrication: Test \#2-4-03

MS slices, 0.35 mm thick were diced into 2 cm squares. The chips will be used for surface preparation and cell fabrication studies of MS slicing.

### 3.8 Cutting Enhancement: Test \#2-5-01

Glass walls were mounted on either side of a 10 cm silicon ingot with standard conditions of MS slicing. This technique has been used very successfully with gallium arsenide and other materials. The cutting action seemed to proceed well, but the glass and ingot eventually broke loose. The result was complete fracture of the work, even though cutting time and blade wear appeared to be comparable to good cutting.

### 3.9 Machine Proof Test: Test \#2-5-02

The second JPL saw was corrected for end stop vertical alignment and was used to cut a 10 cm silicon ingot with 0.15 mm blades and 0.41 mm spacers. Cutting time was 23 hours, but yield was only $42 \%$. The indication is that slurry mix and application technique were not suitably matched to allow good cutting.

TABLE 1
SLICING TEST SUMMARY

| PARAMETER TEST | 2-3-01 | 2-3-02 | 2-3-03 | 2-3-04 |
| :---: | :---: | :---: | :---: | :---: |
| Material | \{100\} Si | \{100\} Si | \{100\} Si | \{100\} Si |
| Size (mm) | 100 | 100 | 100 | 100 |
| Area/Slice . $\left(\mathrm{cm}^{2}\right)$ | 78.54 | 78.54 | 78.54 | 78.54 |
| Blade Thickness (mm) | $0.15 \times 6.35$ | $0.15 \times 6.35$ | $0.15 \times 6.35$ | $0.15 \times 6.35$ |
| Spacer Thickness (mm) | 0.41 | 0.30 | 0.36 | 0.41 |
| Blade Height (mm) | 6.4 | 6.4 | 6.4 | 6.4 |
| Number of Blades | 150 | 155 | 270 | 137 |
| Load (gram/blade) | 85 | 85 | 85 | 85 |
| Stliding Speed (cm/sec) | 67.7 | 64.6 | 61.9 | 71.30 |
| Abrasive (type/grit size) | \#500 SiC | \#600 SiC | \#600 SiC | \#500/600/800S |
| $0 i l$ Volume (liters) | 7.6 (PC) | 7.6 (LUB) | 716 (LUB) | 7.6 (PC) |
| Mix (kg/liter) | 0.36 | 0.36 | 0.36 | 0.36 Total |
| Slice Thickness (mm) | 0.320 | -- | 0.320 | 0.313 |
| Kerf Width (mm) | 0.239 | -- | 0.188 | 0.246 |
| Abrasive Kerf Loss (mm) | 0.086 | -- | 0.036 | 0.094 |
| Cutting Time (hours) | 24.5 | 27.8 | 32.4 | 22.1 |
| Efficiency (full test) | 1.34 |  | 0.87 | 1.45 |
| (typical) | 1.49 | -- | 1.12 | 1.66 |
| (maximum) | 1.69 | -- | 1.30 | 1.94 |
| Abrasion Rate (full test) | 0.077 | -- | 0.046 | 0.087 |
| $\left(\mathrm{cm}^{3} / \mathrm{hr} / \mathrm{bl}\right.$ (typical) | 0.09 | -- | 0.06 | 0.100 |
| (maximum) | 0.10 | -- | 0.07 | 0.117 |
| Productivity (full test) | 3.21 | 2.83 | 2.42 | 3.55 |
| ( $\mathrm{cm}^{2} / \mathrm{hr} / \mathrm{bl}$ ) (typical) | 3.57 | -- | 3.12 | 4.08 |
| (maximum) | 4.05 | -- | 3.63 | 4.76 |
| Yield | 100/149 (67\%) | 0/154 (0\%) | 20-30\% | 113/136(83\%) |
| Stice Taper (mm) | 0.039 | - - |  | 0.040 |
| Slice Bow (mm) | 0.034 | - - |  | 0.051 |
| Abrasive Utilization ( $\mathrm{cm}^{3} / \mathrm{kg}$ ) | 102.9 | 89.0 | 145.7 | 96.7 |
| Oil Utilization ( $\mathrm{cm}^{3} / \mathrm{l}$ iter) | 37.0 | 32.0 | 52.5 | 34.8 |
| Blade Wear Ratio ( $\mathrm{cm}^{3} / \mathrm{cm}^{3}$ ) | 0.039 | 0.049 | 0.060 | 0.046 |

TABLE 1 (cont.)
SLICING TEST SUMMARY

| PARAMETER TEST | 2-4-01 | 2-4-02 |  |
| :---: | :---: | :---: | :---: |
| Material | $\begin{gathered} \{100\} \mathrm{Si} \\ 100 \\ 78.54 \end{gathered}$ | $\begin{gathered} \{100\} \mathrm{Si} \\ 100 \\ 78.54 \end{gathered}$ |  |
| Blade Thickness $(\mathrm{mm})$ <br> Spacer Thickness $(\mathrm{mm})$ <br> Blade Height $(\mathrm{mm})$ <br> Number of Blades  | $\begin{gathered} 0.15 \times 6.35 \\ 0.36 \\ 6.4 \\ 165 \end{gathered}$ | $\begin{gathered} 0.15 \times 6.35 \\ 0.41 \\ 6.4 \\ 150 \end{gathered}$ |  |
| Load (gram/blade) <br> Sliding Speed $(\mathrm{cm} / \mathrm{sec})$ | $\begin{array}{r} 85 \\ 64.8 \end{array}$ | $\begin{array}{r} 85 \\ 64.8 \end{array}$ |  |
| Abrasive (type/grit size) <br> 0 il Volume (liters) <br> Mix $(\mathrm{kg} / \mathrm{li} \mathrm{ter})$ | $\begin{gathered} \# 600 \mathrm{SiC} \\ 7.6 \\ 0.36 \end{gathered}$ | $\begin{gathered} \# 600 \mathrm{SiC} \\ 7.6 \\ 0.36 \end{gathered}$ |  |
| Slice Thickness $(\mathrm{mm})$ <br> Kerf Width $(\mathrm{mm})$ <br> Abrasive Kerf Loss $(\mathrm{mm})$ <br> Cutting Time (hours) | $\begin{array}{r} 0.314 \\ 0.194 \\ 0.042 \\ 22.4 \end{array}$ | $\begin{array}{r} 0.358 \\ 0.201 \\ 0.049 \\ 22.4 \end{array}$ |  |
| Efficiency (full test) <br> (typical) <br>  (maximum) <br>  (full test) <br> Abrasion Rate (typical) <br> $\left(\mathrm{cm}^{3} / \mathrm{hr} / \mathrm{bl}\right.$ (maximum) <br>  (full test) <br> Productivity (typical) <br> (cm $^{2} / \mathrm{hr} / \mathrm{bl}$ ) (maximum) | $\begin{aligned} & 1.24 \\ & 1.47 \\ & 1.67 \\ & 0.068 \\ & 0.08 \\ & 0.09 \\ & 3.51 \\ & 4.16 \\ & 4.72 \end{aligned}$ | $\begin{aligned} & 1.28 \\ & 1.50 \\ & 1.80 \\ & 0.070 \\ & 0.08 \\ & 0.10 \\ & 3.51 \\ & 4.10 \\ & 4.9 ? \end{aligned}$ |  |
| Yield  <br> Slice Taper $(\mathrm{mm})$ <br> Slice Bow $(\mathrm{mm})$ <br> Abrasive Utilization $\left(\mathrm{cm}^{3} / \mathrm{kg}\right)$  <br> Oil Utilization $\left(\mathrm{cm}^{3} / 7 i \mathrm{iter}\right)$ <br> Blade Wear Ratio $\left(\mathrm{cm}^{3} / \mathrm{cm}^{3}\right)$ | $\begin{gathered} 97 / 164(59 \%) \\ 0.074 \\ 0.072 \\ 91.9 \\ 33.1 \\ 0.053 \end{gathered}$ | $\begin{gathered} 75 / 144(50 \%) \\ 0.079 \\ 0.056 \\ 86.5 \\ 31.2 \\ 0.055 \end{gathered}$ |  |

TABLE 1 (cont.)

SLICING TEST SUMMARY

| PARAMETER TEST | 2-5-01 | 2-5-02 |  |
| :---: | :---: | :---: | :---: |
| Material  <br> Size $(\mathrm{mm})$ <br> Area/Slice $\left(\mathrm{cm}^{2}\right)$ | $\begin{gathered} \{100\} \mathrm{Si} \\ 100 \\ 78.54 \end{gathered}$ | $\begin{gathered} \{100\} \mathrm{Si} \\ 100 \\ 78.54 \end{gathered}$ |  |
| Blade Thickness $(\mathrm{mm})$ <br> Spacer Thickness $(\mathrm{mm})$ <br> Blade Height $(\mathrm{mm})$ <br> Number of Blades  | $\begin{gathered} 0.15 \times 6.35 \\ 0.30 \\ 6.4 \\ 120 \end{gathered}$ | $\begin{gathered} 0.15 \times 6.35 \\ 0.41 \\ 6.4 \\ 150 \end{gathered}$ |  |
| Load (gram/blade) <br> Sliding Speed $(\mathrm{cm} / \mathrm{sec})$ | $\begin{array}{r} 85 \\ 63.5 \end{array}$ | $\begin{array}{r} 85 \\ 66.9 \end{array}$ |  |
| Abrasive (type/grit size) <br> Oil Volume (liters) <br> Mix (kg/liter) | $\begin{gathered} \# 600 \mathrm{SiC} \\ 7.6 \\ 0.36 \end{gathered}$ | $\begin{gathered} \# 600 \mathrm{SiC} \\ 7.6 \\ 0.36 \end{gathered}$ |  |
| Slice Thickness $(\mathrm{mm})$ <br> Kerf Width $(\mathrm{mm})$ <br> Abrasive Kerf Loss $(\mathrm{mm})$ <br> Cutting Time (hours) | $23.4$ | $\begin{aligned} & 0.334 \\ & 0.225 \\ & 0.073 \\ & 23.0 \end{aligned}$ |  |
| Efficiency (full test) <br> (typical) <br>  (maximum) <br> Abrasion Rate (full test) <br> (cm ${ }^{3} / \mathrm{hr} / \mathrm{bl}$ (typical) <br>  (maximum) <br> Productivity (full test) <br> $\left(\mathrm{cm}^{2} / \mathrm{hr} / \mathrm{bl}\right.$ ) (typical) <br>  (maximum) |  | $\begin{aligned} & 1.36 \\ & 1.47 \\ & 2.05 \\ & 0.077 \\ & 0.08 \\ & 0.12 \\ & 3.42 \\ & 3.70 \\ & 5.16 \end{aligned}$ |  |
| Yield <br> Slice Taper (mm) <br> Slice Bow (mm) <br> Abrasive Utilization $\left(\mathrm{cm}^{3} / \mathrm{kg}\right)$ <br> 0il Utilization ( $\mathrm{cm}^{3} / 1 i t e r$ ) <br> Blade Wear Ratio $\left(\mathrm{cm}^{3} / \mathrm{cm}^{3}\right)$ | $\begin{gathered} 0 / 119(0 \%) \\ -- \\ -- \\ 68.9 \\ 24.8 \\ 0.047 \end{gathered}$ | $\begin{gathered} 63 / 149(42 \%) \\ 0.069 \\ 0.051 \\ 96.9 \\ 34.9 \\ 0.049 \end{gathered}$ | . |

### 4.0 WAFER CHARACTERIZATION

Table 2 shows a summary of wafer thickness, bow and taper characterization for cutting tests performed during the past quarter. All tests involving standard cutting conditions show poor accuracy characteristics. This seems to be a result of the effectively higher abrasive concentration resulting from the reciprocating slurry system. The wafers resulting from the \#500 SiC show high accuracy cutting, even those from the mix of three abrasive sizes. The kerf loss of \#500 SiC is excessive, and will not allow cost effective cuttinq. The yield was so low with the thin Lubrizol suspension agent, that no characterization was possible. This, again, may be a result of effectively too high an abrasive mix due to increased slurry transport with the low viscosity oil.

### 5.0 DISCUSSION

### 5.1 Blade Misalignment

An important concept in understanding the present limits of MS slicing and in improving the state of the art is that of blade misalignment. Because of the stacked construction of a multiple blade package, both horizontal misalignment (runout) and vertical misalignment (tipping) of blades are expected. This misalignment is controlled by the inaccuracy of blades and spacers and the number of components. Previous estimates of blades and spacers indicated that an average end-to-end runout of as much as $50 \mu$ ( 0.002 inch) was expected within a 225 blade package.

A blade package of this size was tensioned within a bladehead and aligned parallel on each end within $2.5 \mu$ ( 0.0001 inch) by standard techniques. A precision inspection bench was used to measure the exact position of each blade within the package.

| TEST |  |  | 2-3-01 | 2-3-02 | 2-3-03 | 2-3-04 |
| :---: | :---: | :---: | :---: | :---: | :---: | :---: |
| SLICE | Diameter | (mm) | 100 | 100 | 100 | 100 |
|  | Area | $\left(\mathrm{cm}^{2}\right)$ | 78.5 | 78.5 | 78.5 | 78.5 |
| THICKNESS | Average |  | 320 | - - | 320 | 313 |
|  | Std. Dev. | $\mu$ | 24 | - | 71 | 18 |
| TOTAL VARIATION | Average | $\mu$ | 34 | - | 91 | 36 |
|  | Std. Dev. | $\mu$ | 14 | - - | 58 | 22 |
| STD. DEVIATION | Average |  | 12 | - - | 38 | 14 |
|  | Std. Dev. | $\mu$ | 6 | - - | 25 | 9 |
| VERTICAL TTV | Average |  | 40 | - | - - | 40 |
|  | Maximum | $\mu$ | 99 | - - | - - | 120 |
|  | Minimum | $\mu$ | 13 | - - | - - | 24 |
| HORIZONTAL TTV | Average |  | 16 | - - | - - | 10 |
|  | Maximum |  | 31 | - - | - - | 24 |
|  | Minimum | $\mu$ | 5 | - - | - - | 3 |
| VERTICAL BOW | Average | $\mu$ | 40 | - - | - - | 53 |
|  | Maximum |  | 112 | - - | - - | 157 |
|  | Minimum | $\mu$ | 8 | - - | $\cdots$ | 28 |
| HORIZONTAL BOW | Average | $\mu$ | 15 | - - | - - | 16 |
|  | Maximum | $\mu$ | 58 | - - | - - | 40 |
|  | Minimum | $\mu$ | 4 | - - | - - | 6 |
| VERTICAL CL BOW | Average | $\mu$ | 68 | - - | - - | 102 |
|  | Maximum | $\mu$ | 141 | - | - - | 216 |
|  | Minimum | $\mu$ | 36 | - - | - - | 55 |
| HORIZONTAL CL BOW | Average | $\mu$ | 29 | - - | - - | 31 |
|  | Maximum | $\mu$ | 99 | - - | - - | 57 |
|  | Minimum | $\mu$ | 8 | - - | - - | 16 |

TABLE 2 (cont.)

## WAFER THICKNESS CHARACTERIZATION <br> SUMMARY

| - TEST |  |  | 2-4-01 | 2-4-02 | 2-5-01 | 2-5-02 |
| :---: | :---: | :---: | :---: | :---: | :---: | :---: |
| SLICE | Diameter | (mm) | 100 | 100 | 100 | 100 |
|  | Area | $\left(\mathrm{cm}^{2}\right)$ | 78.5 | 78.5 | 78.5 | 78.5 |
| THICKNESS | Average | $\mu$ | 314 | 358 | - - | 334 |
|  | Std. Dev. | $\mu$ | 33 | 56 | - - | 36 |
| TOTAL VARIATION | Average | $\mu$ | 62 | 66 | - - | 65 |
|  | Std. Dev. | $\mu$ | 23 | 43 | - | 28 |
| STD. DEVIATION | Average | $\mu$ | 26 | 28 | - - | 25 |
|  | Std. Dev. | $\mu$ | 11 | 19 | - - | 12 |
| VERTICAL TTV | Average | $\mu$ | 74 | 79 | - | 69 |
|  | Maximum | $\mu$ | 150 | 184 | - - | 118 |
|  | Minimum | $\mu$ | 30 | 22 | - - | 32 |
| HORIZONTAL TTV | Average | $\mu$ | 16 | 13 | - - | 14 |
|  | Maximum | $\mu$ | 33 | 30 | - | 21 |
|  | Minimum | $\mu$ | 4 | 4 | - - | 7 |
| VERTICAL BOW | Average | $\mu$ | 82 | 69 | - - | 61 |
|  | Maximum | $\mu$ | 140 | 132 | - - | 159 |
|  | Minimum | $\mu$ | 29 | 13 | - - | 17 |
| HORIZONTAL BOW | Average | $\mu$ | 19 | 18 | - - | 20 |
|  | Maximum | $\mu$ | 46 | 46 | - - | 46 |
|  | Minimum | $\mu$ | 4 | 7 | - - | 4 |
| VERTICAL CL BOW | Average | $\mu$ | 144 | 101 | - - | 102 |
|  | Maximum | $\mu$ | 204 | 182 | - - | 211 |
|  | Minimum | $\mu$ | 80 | 28 | - - | 20 |
| HORIZONTAL CL BOW | Average | $\mu$ | 33 | 32 | - - | 38 |
|  | Maximum | $\mu$ | 67 | 79 | - - | 73 |
|  | Minimum | $\mu$ | 11 | 14 | - - | 16 |

Figure 1 shows the reduction of this information to indicate the runout of each blade. An average runout of $41 \mu$ ( 0.0016 inch) was measured over 12 inches of the 15 inch package. This implies a full end to end runout averaging $50 \mu$ ( 0.0020 inch) exactly that predicted from the thickness distribution of blades and spacers. Therefore, the assumption of significant misalignment within a package is valid, and the need for an alignment correction technique toi improve alignment and to allow more blades to be used simultaneously is obvious.

The blade alignment device was used on blade packages during the final month of this reporting period. The engagement of the device onto a package proved to be very difficult. Not all blades will engage with their respective gear teeth, and correction of this condition is difficult. At the end of this reporting period an alignment device was successfully installed on a fully tensioned blade package (150 $0.15 \mathrm{~mm} \times 6.35 \mathrm{~mm}$ blades and 0.35 mm spacers). The device seemed to improve the parallelism of the package. The natural parallelism of a tensioned blade package is only 100 ( 0.004 inch). This is corrected by varying the compression on either end of a blade package. With the alignment device, the basic parallelism was on the order of $3 \mu$ ( 0.0001 inch). This blade package will be used in a cutting test during the end of September.

### 5.2 Abrasive Slurry

At the moment, silicon carbide is the best and most cost effective abrasive available. We hope to reduce the costs through reclamation and broader abrasive sizing (as in test \#2-3-04).

Much of the cust of abrasive arises from the process of separating a narrow band of particle sizes. In slurry sawing, only the largest particles are felt to do work, and the smaller particles go along for the ride (as long as there are not too

many small particles). We are currently running tests on mixtures of grits to see if we can use a broader spectrum of particle sizes.

It appears that the failure mechanism of slurry is accumulation of debris rather than suspension agent breakdown or abrasive fracture or dulling. If debris can be removed, the rest of the slurry should be reusable. We have contacted a manufacturer as to the possibility of filtering the slurry. We are also considering centrifugal separation.

### 5.3 Prototype Design Concepts

A prototype MS saw is being designed in order to increase the number of blades used from 300 to 1000 , reducing the specific labor and capitalization costs of MS slicing. Four separate configurations of the saw have been developed involving variations in the method of protecting moving parts from the abrasive slurry. Two other concepts involved means of providing the feed motion of cutting. By far, the important decision involves the protection from slurry.

The large tensioning capacity required of the bladehead ( $600,000 \mathrm{lbs}$.$) and the necessary stiffness of that component$ makes the bladehead a very heavy piece. For that reason, a fundamental consideration was made to provide the reciprocating motion for cutting by a work-piece moving action. Two systems were devised to provide the vertical cutting stroke necessary. in one, the reciprocating drive system is raised into the bladehead, and in the other, the heavy bladehead is lowered onto the reciprocating workpiece. The lowered bladehead was selpeted since the resulting reaclion loads were minimal.

Stiffness calculations on the linear ball bushing and rod drive and feed mechanisms allowed the selection and purciiase of these components. These components are common to all design concepts which were considered.

Because of the need to protect mechanisms from abrasive slurry, and to allow suitable operating conditions, the choice of machine configuration was not simple. The first concept involved a large pan with an outer trough which would move with the workpiece. The pan protected the sliding system beneath it, and drained slurry into two stationary troughs for recirculation. This mechanism was fabricated, mounted onto a saw for simulated operation and run with slurry pouring onto it. The slurry did not drain well as the high viscosity fluid would accumulate on the large surface area. Standing waves resulted, and drainage points provided splashing at the ends of the stroke. The large area required for this system was not desirable either.

A second configuration relied on gravity to protect the sliding mechanism. The workpiece support dropped downward from the slide, turning upward beyond a protecting screen to support the silicon ingot adjacent to the blades. This system offered the smallest configuration, but the lateral stiffness and manufacture of the tubular support system were important drawbacks of this design.

A similar system placed the drive mechanism above the bladehead, with the workpiece slung below the blades. Access to the bladehead during setup was another drawback to this system. If "upside-down" cutting were feasible, this system would be ideal. A test will be conducted during the next quarter to demonstrate the feasibility of the upside-down ingot configuration of MS slicing.

A final concept involved a shield inside the drive components which raised above and around the sides of the bladehead. The shield had to be larger than the bladehead length plus the stroke length. It was calculated that the bladehead length would be over 100 cm ( 40 inches) due to the stiffness requirements. For that reason, this configuration became too unwieldy.

The technique of baffle shielding was considered instead of a bellows protection of the linear ball bushings and rods. Rubber bellows could not stand up to the long lifetime and high reciprocating speeds ( $>60 \mathrm{~cm} / \mathrm{sec}$ ). The added problem of slurry acting on these rubber boots presented an unknown additional problem. Also, in order to accommodate the bellows size, the length and diameter of the rods would have to be excessive.

The designs described above are shown in the first drawings in Appendix I. A review of the concepts indicated that advantages and disadvantages of each required a modified design. An improved version of the underslung design is now in progress, with better stiffness and manufacturing ease to the ingot support carriage. This appears to be the final design concept.

### 5.4 Prototype Drive Mechanism

The drive mechanism for the large MS saw was considered independently from the full machine configuration. In order to minimize the power requirement for the drive, a flywheel was chosen. This allows a conservative motion system for the drive. An ultimate flywheel involves an infinite inertial mass flywheél and an infinitely long connecting rod. An analysis was conducted to determine the necessary flywheel mass and connecting rod length.

A 200 1b. reciprocating mass and 10 inch cutting stroke were chosen as a basis for the design. The configuration chosen was that shown in Figure 2. A solid connecting rod replaces the scotch yoke type used in present machines. The equations of motion for this configuration are:

$$
\begin{equation*}
\ddot{\theta}=\dot{\theta}^{2} \frac{\cos \theta \sin \theta+\frac{\cos \theta\left(3 \sin ^{2} \theta-1\right)}{L^{*}}+\frac{\sin \theta \cos \theta\left(2 \sin ^{2} \theta-1\right)}{L^{*^{2}}}+\frac{\cos ^{3} \theta \sin ^{2} \theta}{L^{*^{3}}}+\frac{\cos ^{3} \theta \sin ^{3} \theta}{L^{*^{4}}}}{I^{*}+\cos ^{2} \theta+\frac{2 \cos ^{2} \theta \sin \theta}{L^{*}}+\frac{\cos ^{2} \theta \sin ^{2} \theta}{L^{*^{2}}}} \tag{1}
\end{equation*}
$$

$$
\frac{\ddot{x}}{r}=\ddot{\theta}\left(\cos \theta+\frac{\sin \theta \cos \theta}{L^{*}}\right)+\dot{\theta}^{2}\left(-\sin \theta+\frac{1-2 \sin ^{2} \theta}{L^{*}}-\frac{\cos ^{2} \theta \sin ^{2} \theta}{L^{*}}\right)
$$

where

$$
\begin{align*}
& I^{*}=I / M r^{2} \\
& L^{*}=L / r \tag{2}
\end{align*}
$$

Two cases were considered in order to choose the appropriate connecting rod length, or L* , and flywheel inertia, or I* . The equations of motion were simulated with numerical integration under natural motion. For the selection of the flywheel, the connecting rod was allowed to be very long. For the condition $L^{*}=\infty$, the equations of motion reduce to

$$
\begin{align*}
& \ddot{\theta}=\dot{\theta}^{2} \frac{\cos \theta \sin \theta}{I^{\star}} \\
& \frac{\ddot{x}}{r}=\ddot{\theta} \cos \theta-\dot{\theta} \sin \theta \tag{3}
\end{align*}
$$



FIGURE 2
SCHEMATIC OF RECIPROCATING DRIVE

Figure 3 shows the simulation of one cycle of motion for various values of $I^{*}$. Only a $12 \%$ increase in peak natural acceleration occurs for $I^{*}=3$, therefore, a flywheel matching this condition will be used.

The motion of the driven mass under fixed rotational speed ( $\dot{\theta}=$ constant) was simulated for various values or $L^{*}$ and is shown in Figure 4. For a value of $L^{*}=8$, only a $13 \%$ increase in peak acceleration occurs. This is the second design choice for the prototype drive system.

Figure 5 shows the acceleration of a driven mass under natural motion with $I^{*}=3$ and varying values of $L^{*}$. $A$ value of $L^{*}$ of more than 8 will be used. The motor drive will only be required to supply less than $20 \%$ of the reciprocating drive requirement, plus the friction losses and cutting drag power.

### 5.5 Solar Cell Fabrication

Fabrication of solar cells from 10 cm diameter MS slices of silicon has been arranged and subcontracted on a preliminary basis. Both full 10 cm diameter and 2 cm square wafers will be fabricated. The 2 cm fabrication will be useful to indicate proper use of the MS wafer surface, while 10 cm diameter slices will demonstrate the problems associated with solar cells made from the thin slices and distinct surface of the MS technique.

Fabrication in both modes will be used in conjunction with the surface preparation development. Results of baseline fabrication and preliminary surface preparation work should be available by the end of the next quarter.




### 5.6 Wafer Surface Preparation

The first series of surface preparation experiments have been planned and subcontracted. 0.30 to 0.35 mm thick silicon slices, both 10 cm diameter and 2 cm square, are being prepared by syton polishing, cupric ion polishing, planar etching and texture etching to depths of $5,10,15$ and 20 microns (nominal). Groups of each size wafer will be prepared according to this matrix. One prepared slice of each grouping will be retained for SEM micrography and damage characterization. The remaining slices will be fabricated into solar cells and characterized for $V_{o c}, I_{S C}$, fill factor and efficiency against baseline slices. From these results, a technique of minimal material removal, suitable for MS slices will be established.
6.0 CONCLUSIONS AND RECOMMENDATIONS

- Blade misalignment has been shown to cause a reduction of wafer yield and accuracy. As a result of testing, an improvement in tipping accuracy has been developed as a modification to existing equipment.
- The blade alignment device is proving very difficult to use. Proper engagement of the rack gears with the blades is difficult to achieve.
- Measurements of blade misalignment supports earlier statistical evaluation of a multiblade package.
- Proper MS cutting action is only achieved with a proper combination of abrasive size, mix, application technique and oil type. The choice is critical when dealing with large diameter, thin slices and minimal stability blades for low kerf loss.

Plans for the next quarter include:

- Order 12 cm silicon ingot for cutting tests.
-. Complete wafer strength tests.
- Complete laboratory saw.
- Evaluate preliminary cell fabrication/surface preparation results. Plan next test sequence.
- Improve technique of blade alignment. Demonstrate impact on cutting.
- Begin final design/fabrication of large scale prototype.
- Continue slurry/blade development.


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## APPENDIX I

- New Technology
- Engineering Drawings \& Sketches


## NEW TECHNOLOGY

A "Multiple Blade Alignment Device" described in previous reports has been reported to JPL as an item of New Technology. The device was conceived as a portion of Phase II of this contract, and is presently under develop-. ment. A patent on the "Multiple Blade Alignment Device" is currently being pursued by the Varian Patent Office. Actual use of the technique with MS slicing is anticipated in late September and October of 1977.

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## APPENDIX II

- Man-Hours and Costs
- Program Plan (Updated)


## MAN-HOURS AND COSTS (PHASE II)

During the reporting period of June 18, 1977 to September 18, 1977, total man-hours were 2101.3 hours and total costs were $\$ 85,986$. Previous expenditures were 558.0 hours and $\$ 50,256$. As of September 18, 1977, total program man-hours were 2659.3 hours and total program costs were $\$ 136,242$.

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Phase II
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Program Plan
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Varian Associates/Lexington Vacuum Division
Phase II Program Plan
Starting Date: 1/9/76 (I) 5/19/77 (II)


Varian Associates/Lexington Vacuum Division
Phase II
Starting Date: 1/9/76 (I) 5/19/77 (II)

Task 9 Work Moving Drive Conceptual Design Analysis/Specifications Design
Purchased Items
Task 10 Feed Mechanism Conceptual Design
Analysis/Specifications Design
Purchased Items
Task 11 Bladehead
Structural Analysis
Specifications
Design
Task 12 Blade Tensioning Conceptual Design
Analysis/Specifications Design
Fabrication

|  | 1977 |  |  |  |  | 1978 |  |  |  |  |  |  |  |  | 1979 |  |  |  |  |  |
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SLICING OF SILICON INTO SHEET MATERIAL
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Varian Associates/Lexington Vacuum Division Phase II
JPL Contract 954374 Program Plan
Starting Date: 1/9/75 (I) 5/19/77 (II)
PROJECT MILESTONES
(PHASE II)
PROCESS INTERFACE
Task 17 Comp. Cost Analysis Identify Cost Elements Baseline Cost Analysis Update - MS Slicing Other Slicing Techniques
Task 18 Cell Fabrication Fabricate Standard Slices Fabricate Prepared Wafers Evaluate $V_{0 C}$, $I_{S C}$, $F F$, eff.

Task 19 Surface Preparation Chem/Mech. Damage Removal Combined Removal Techniques Evaluate Cell Performance Damage Characterization Optimize Removal Techniques
Task 20 Mech. Wafer Testing Design/Fabricate 4 Point Bending Fixture
Background Analysis Test Wafer Strength Specify Handiing/Eutting Limitations of Wafers


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SLICING OF SILICON INTO SHEET MATERIAL

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DIRECT LABOR (HOURS 000 OMITTED)


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